

# **FPD Materials & Components Japan TC Chapter and FPD Metrology Japan TC Chapter Joint Meeting Meeting Summary and Minutes**

**SEMI Japan Standards Spring 2015 Meetings**  
April 10, 2015, 14:00-17:00  
SEMI Japan, Tokyo, Japan

**Next Committee Meeting**  
**FPD Materials & Components Japan TC Chapter:**  
**SEMI Japan Standards Summer 2015 Meetings**  
Monday, July 27, 2015, 15:00-17:00  
SEMI Japan, Tokyo, Japan

**FPD Metrology Japan TC Chapter:**  
**SEMI Japan Standards Fall 2015 Meetings**  
October, 2015 (TBD)  
SEMI Japan, Tokyo, Japan

## **Table 1 Meeting Attendees**

**Co-Chairs of FPD M&C Committee:** Tadahiro Furukawa (Yamagata University), Yoshi Shibahara (Fujifilm)  
**Co-Chairs of FPD Metrology Committee:** Ryoichi Watanabe (Japan Display), Akira Kawaguchi (Otsuka Electronics)  
**SEMI Staff:** Naoko Tejima (SEMI Japan)

<i>Company</i>	<i>Last</i>	<i>First</i>	<i>Company</i>	<i>Last</i>	<i>First</i>
Yamagata University	Furukawa	Tadahiro	Fujifilm	Sato	Tadanobu
Teijin	Itoh	Haruhiko	Fujifilm	Shibahara	Yoshi
Otsuka Electronics	Kawaguchi	Akira	Japan Display	Watanabe	Ryoichi
HOYA	Nitobe	Kaname	ITRI	Wen	Chao-Hua
Nitto Denko	Kobayashi	Shigeo	Japan Business Society	Yamagishi	Naomichi
Meiji University	Nagai	Kazukiyo	SEMI Japan	Tejima	Naoko
Konica Minolta.	Ochi	Keizo			

*\* alphabetical order by last name*

## **Table 2 Leadership Changes**

**FPD Materials & Components Japan TC Chapter**

None.

**FPD Metrology Japan TC Chapter**

None.

## **Table 3 Ballot Results**

**FPD Materials & Components Japan TC Chapter**

None.

**FPD Metrology Japan TC Chapter**

None.

**Table 4 Authorized Ballots**  
**FPD Materials & Components Japan TC Chapter**

<i>Document #</i>	<i>When</i>	<i>SC/TF/WG</i>	<i>Details</i>
5555	Cycle 5, 2015	Polarizing Film TF	Revision to SEMI D50-0707, Test Method for Surface Hardness of FPD Polarizing Film with title change to: Test Method for Surface Hardness of FPD components

**FPD Metrology Japan TC Chapter**

None.

**Table 5 Authorized Activities**  
**FPD Materials & Components Japan TC Chapter**

<i>Document #</i>	<i>Type</i>	<i>SC/TF/WG</i>	<i>Details</i>
5555	Revised SNARF	Polarizing Film TF	Revision to SEMI D50-0707, Test Method for Surface Hardness of FPD Polarizing Film with title change to: Test Method for Surface Hardness of FPD components

**FPD Metrology Japan TC Chapter**

None.

**Table 6 New Action Items**  
**FPD M&C Japan TC Chapter**

<i>Item #</i>	<i>Assigned to</i>	<i>Details</i>
FPD M&C 150206-03	SEMI Staff	To forward adjudication result of Doc.#5796 to the ISC A&R Subcommittee for procedural review.
FPD M&C 150206-04	SEMI Staff	To forward adjudication result of Doc.#5797 to the ISC A&R Subcommittee for procedural review.
FPD M&C 150206-05	SEMI Staff	To forward adjudication result of Doc.#5798 to the ISC A&R Subcommittee for procedural review.
FPD M&C 150206-06	SEMI Staff	To forward adjudication result of Doc.#5799 to the ISC A&R Subcommittee for procedural review.
FPD M&C 150410-01	Polarizing Film TF	To submit the ballot of SEMI D50 (#5555) for Cycle 5, 2015
FPD M&C 150410-02	Flexible Display TF	To check whether there are the existences of the patented technology in the Doc. 5551, and to discuss a way not to include the patented technologies.
FPD M&C 150410-03	Flexible Display TF	To submit the new SNARF of Doc. #5551 3-week before the next Japan TC Chapter meeting (by July 6).

**FPD Metrology Japan TC Chapter**

<i>Item #</i>	<i>Assigned to</i>	<i>Details</i>
FPD Metrology 150410-01	SEMI Staff	To contact the co-leaders of D31 Revision TF (Kose Tanahashi and Masao Kochi) and ask their intention.

## [Common Part 1]

### 1 Welcome, Reminders, and Introductions

Tadahiro Furukawa, committee co-chair, called the meeting to order at 14:00. Self-introductions were made followed by the agenda review.

### 2 Required Meeting Elements

The meeting reminders on antitrust issues, intellectual property issues and holding meetings with international attendance were reviewed by SEMI staff, Naoko Tejima.

### 3 SEMI Staff Report

Naoko Tejima gave the SEMI staff report. This report included SEMI Global 2015 Calendar of Events, Global Standards Meeting Schedule, 2015 Critical Dates for SEMI Standards Ballots, SEMI Standards Publication, A&R Ballot Review, Updated Template, and Contact Information.

Follow-up revisions of *Regulations* and *Procedure Manual* were published on 27 March, 2015 for use in NA Spring Standard meetings and it was briefly introduced by Junko Collins.

**Attachment:** 01\_SEMI\_Staff\_Report\_150410

**Attachment:** 02\_ISC Subcommittee on the Regulations\_150410

### 4 Liaison Reports

#### 4.1 Korea FPD Committee Report

Naoko Tejima reported for the Korea FPD Metrology Committee. This report included Leadership, Organization Chart, Meeting Information, Major Updates, Subcommittee /TF/WG Updates” and Contact Information.

**Attachment:** 03\_KR\_FPD\_Liaison\_Report\_150410

#### 4.2 Taiwan FPD Committee Report

Naoko Tejima reported for the Taiwan FPD Committee. This report included FPD Metrology Standard Committee Organization Chart, FPD Standard Committee Highlights, FPD Committee Meeting Information and Contact Information.

**Attachment:** 04\_TW\_FPD\_Liaison\_Report\_150410

## [Japan FPD Materials & Components Committee Part]

### 5 Review of Previous Meeting Minutes

The committee reviewed the minutes of the previous meeting held on February 6, 2015.

**Motion:** To approve the minutes of the previous meeting as written.

**By / 2<sup>nd</sup>:** Yoshi Shibahara (Fujifilm) / Ryoichi Watanabe (Japan Display)

**Discussion:** None

**Vote:** 10 in favor and 0 opposed. **Motion passed.**

**Attachment:** 05\_JA\_FPD\_M&C\_Previous\_Mtg\_Minutes\_150410

## 6 Task Force Reports

### 6.1 Polarizing Film Task Force

Yoshi Shibahara reported for the Polarizing Film Task Force. The Task Force met earlier in the day. Of note:

- Working for Doc. #5555, Revision to SEMI D50-0707, Test Method for Surface Hardness of FPD Polarizing Film.
- Revise SNARF to expand the scope of D50 from the polarizing Film to FPD Components.

**Motion:** To approve the revised SNARF for “Revision to SEMI D50-0707, Test Method for Surface Hardness of FPD Polarizing Film with title change to: Test Method for Surface Hardness of FPD components” to expand the scope.

**By / 2<sup>nd</sup>:** Yoshi Shibahara (Fujifilm) / Shigeo Kobayashi (Nitto Denko)

**Discussion:** None.

**Vote:** 11 in favor and 0 opposed. **Motion passed.**

**Motion:** To submit the Doc. 5555, “Revision to SEMI D50-0707, Test Method for Surface Hardness of FPD Polarizing Film with title change to: Test Method for Surface Hardness of FPD components” for Cycle 5, 2015.

**By / 2<sup>nd</sup>:** Yoshi Shibahara (Fujifilm) / Shigeo Kobayashi (Nitto Denko)

**Discussion:** None.

**Vote:** 11 in favor and 0 opposed. **Motion passed.**

**Action Item:** Polarizing Film Task Force to submit the ballot of SEMI D50 (#5555) for Cycle 5, 2015

Shigeo Kobayashi reported that TF had been discussing about Specification of dimensions of polarizer and related materials especially for non-rectangular shape as new business.

**Attachment:** 06\_Polarizing\_Film\_TF\_Report\_150410

### 6.2 Flexible Display Task Force

Haruhiko Itoh reported on progress for the Flexible Display Task Force. The Task Force met earlier in the day. Of note:

- Working for Doc. #5551, *New Standard: Test Method for Measurement of Water Vapor Transmission Rate for Plastic Films and Sheets with High Barrier Properties for Electronic Devices.*
- There is possibility to include the Patented Technologies in the Doc. #5551. TF will check it again and discuss a way not to include the patented technologies.
- If it is known that patented technology is intended to be included in the proposed Document(s), then the proposer shall inform Standards Staff. Standards staff shall then request and obtain a letter of intent (LOI) from the holder(s) of the patented technology (hereinafter called patent holder(s)). (Regulation 16.2.1)

**Action Item:** Flexible Display Task Force to check whether there are the existences of the patented technology in the Doc. 5551, and to discuss a way not to include the patented technologies.

**Action Item:** Flexible Display Task Force to submit the new SNARF of Doc. #5551 3-week before the next Japan TC Chapter meeting (by July 6).

### 6.3 Color Filter Task Force

Tadahiro Furukawa reported for the Color Filter Task Force that there were no particular things should be reported.

### 6.4 FPD Mask Task Force

Kaname Nitobe reported for the FPD Mask Task Force that there were no particular things should be reported.

## 7 Old Business

### 7.1 Previous Meeting Action Items

Naoko Tejima reviewed the previous meeting action items.

**Table 7 Previous Meeting Actions Items**

<i>Item #</i>	<i>Assigned to</i>	<i>Details</i>
FPD M&C 150206-01	SEMI Staff	To correct start time of the next FPD Metrology Japan TC Chapter meeting to <u>14:00</u> of the previous meeting minutes. ... <b>Close</b>
FPD M&C 150206-02	SEMI Staff	To correct FPD M&C 140418-01 in Table 7 Previous Meeting Action Items to “ <u>to contact Backlight Task Force co-leaders</u> ” of the previous meeting minutes. ... <b>Close</b>
FPD M&C 150206-03	SEMI Staff	To forward adjudication result of Doc.#5796 to the ISC A&R Subcommittee for procedural review. ... <b>Open</b>
FPD M&C 150206-04	SEMI Staff	To forward adjudication result of Doc.#5797 to the ISC A&R Subcommittee for procedural review. ... <b>Open</b>
FPD M&C 150206-05	SEMI Staff	To forward adjudication result of Doc.#5798 to the ISC A&R Subcommittee for procedural review. ... <b>Open</b>
FPD M&C 150206-06	SEMI Staff	To forward adjudication result of Doc.#5799 to the ISC A&R Subcommittee for procedural review. ... <b>Open</b>
FPD M&C 150206-07	Polarizing Film Task Force	To send the revised SNRAF of Doc. #5555 to SEMI until March 15 for 2 weeks review by TC Members. ... <b>Close</b>
FPD M&C 150206-08	SEMI Staff	To send the revised SNRAF of Doc. #5555 to Global TC Members to review for 2 weeks. ... <b>Close</b>

## 8 New Business

None.

### [Japan FPD Metrology Committee Part]

## 9 Review of Previous Meeting Minutes

The committee reviewed the minutes of the previous meeting held on April 18, 2014.

**Motion:** To approve the minutes of the previous meeting as written.

**By / 2<sup>nd</sup>:** Akira Kawaguchi (Otsuka Electronics) / Haruhiko Itoh (Teijin)

**Discussion:** None

**Vote:** 11 in favor and 0 opposed. **Motion passed.**

**Attachment:** 07\_JA\_FPD\_M&C\_&\_Metrology\_Previous\_Mtg\_Minutes\_150410

## 10 Task Force Reports

### 10.1 D31 Revision Task Force

Keizo Ochi reported on progress for the *D31 Revision* Task Force that there were no particular things should be reported.:

## 11 Old Business

### 11.1 Previous Meeting Action Items

None.

## **12 New Business**

None.

### **[Common Part 2]**

## **13 New Business of FPD Coordination Group**

FPD Coordination Group meeting will be held on May 29, and will discuss the FPD Workshop should be held or not.

## **14 Action Item Review**

### *14.1 New Action Items*

Naoko Tejima reviewed the new action items. These can be found in the New Action Items table at the beginning of these minutes.

## **15 Next Meeting and Adjournment**

The next meeting of the FPD Materials & Components Japan TC Chapter is scheduled for Monday, July 27, 2015, 15:00-17:00, SEMI Japan, Tokyo, Japan

The next meeting of the FPD Metrology Japan TC Chapter is scheduled for October (TBD).

Respectfully submitted by:  
Naoko Tejima  
Manager, Standards  
SEMI Japan  
Phone: +81.3.3222.5804  
Email: ntejima@semi.org

Minutes approved by:

Tadahiro Furukawa (Yamagata University), Co-chair of FPD Materials & Components Japan TC Chapter	May. 28, 2015
Yoshi Shibahara (Fujifilm) , Co-chair of FPD Materials & Components Japan TC Chapter	May. 27, 2015
Ryoichi Watanabe (Japan Display), Co-chair of FPD Metrology Japan TC Chapter	May. 27, 2015
Akira Kawaguchi (Otsuka Electronics) , Co-chair of FPD Metrology Japan TC Chapter	May. 28, 2015

**Table 8 Index of Available Attachments #1**

#	<i>Title</i>
1	SEMI_Staff_Report_150410
2	ISC_Subcommittee_on_the_Regulations_150410
3	KR_FPD_Liaison_Report_150410
4	TW_FPD_Liaison_Report_150410
5	JA_FPD_M+C_Previous_Mtg_Minutes_150410
6	Polarizing_Film_TF_Report_150410
7	JA_FPD_M+C_Metrology_Previous_Mtg_Minutes_150410

#1 Due to file size and delivery issues, attachments must be downloaded separately. A .zip file containing all attachments for these minutes is available at [www.semi.org](http://www.semi.org). For additional information or to obtain individual attachments, please contact Naoko Tejima at the contact information above.